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(54) SEPARATION COLUMN OF RESIN CAPABLE
OF FOLLOWING UP TO CHARGE OF
EFFECTIVE RESIN SURFACE

(57) Abstract:

PURPOSE: To provide a sepn. column of a resin capable of following up to charge of effective resin surface which can separate and transfer a cation resin without allowing an anion resin to remain therein and without removing the cation resin by constituting the discharging port for the anion resin in the sepn. column in such a way that it can follow up the fluctuation in the resin sepn. surface.

CONSTITUTION: A satd. resin wherein an anion resin and a cation resin is mixed is charged 3 into a shell 2, and the resin mixture is scrubbed by air for mixing the resins to be introduced 6 into a header 7. The clads sticking to the resin surfaces are stripped and are suspended in the backwashing water from the header 7. The suspended clads are discharged 5 to the outside of the column. On the other hand, the resins are settled in the backwashing water by backwashing and are separated to two layers. The operator rotates a disc 13 to a prescribed extent by a driving device 12 so as to position the forward end part of a movable pipe 15 in the optimum position of the sepn. surface after check-

ing visually the sepn. surface. Only the anion resin is transferred into an anion resin regeneration column by the pressure of the air for transfer to be introduced 4 into said column. The remaining cation resin is transferred 4 into a cation resin regeneration column by the air pressure through the discharging port 8 in the lower part of the sepn. column, whereby the sepn. and transfer of the resins are completed.

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